In the Claims:

1. (Original) A composition for removing residues from the microstructure of an object comprising:

carbon dioxide;

an additive for removing the residues comprising a fluoride having a formula $NR_1R_2R_3R_4F$, where R_1 , R_2 , R_3 , and R_4 are each independently a hydrogen or an alkyl group; and

a co-solvent for dissolving said additive in said CO₂ at a pressurized fluid condition.

- 2. (Original) The composition of claim 1 wherein the additive further comprises a basic compound.
- 3. (Original) The composition of claim 1 wherein R_1 , R_2 , R_3 , and R_4 are hydrogen.
- 4. (Original) The composition of claim 1 wherein R_1 , R_2 , R_3 , and R_4 are an alkyl group.
- 5. (Original) A composition for removing residues from the microstructure of an object comprising:

carbon dioxide,

- a compound having a hydroxyl group,
- a fluoride having a formula $NR_1R_2R_3R_4F$, where R_1 , R_2 , R_3 , and R_4 are each independently a hydrogen or an alkyl group.
- 6. (Original) The composition of claim 5 further comprising a basic compound.
- 7. (Original) The composition of claim 6 wherein the basic compound is selected from a quatenaryammoniumhydroxide, an alkylamine, an alkanolamine, a hydroxylamine, and mixtures thereof.
- 8. (Original) The composition of claim 5 further comprising a co-solvent selected from dimethylacetamide, propylene glycol, dimethylsulfoxide, deionized water, acetic acid, and mixtures thereof.

- 9. (Original) The composition of claim 8 wherein the co-solvent comprises deionized water.
- (Original) The composition of claim 8 wherein the co-solvent is substantially free of water.
- 11. (Original) The composition of claim 5 wherein R₁, R₂, R₃, and R₄ are hydrogen.
- 12. (Original) The composition of claim 5 wherein R_1 , R_2 , R_3 , and R_4 are an alkyl group.
- 13. (Original) The composition of claim 5 wherein the fluoride is selected from ammonium fluoride, tetramethylammoniumfluoride, tetraethylammoniumfluoride, tetrabutylammoniumfluoride, tetrapropylammoniumfluoride, choline fluoride, and mixtures thereof.
- 14. (Original) The composition of claim 5 wherein the compound is selected from ethanol, methanol, n-propanol, isopropanol, n-butanol, iso-butanol, diethyleneglycolmonomethylether, diethyleneglycolmonoethylether, hexafluoroisopropanol, and mixtures thereof.
- 15. (Canceled)
- 16. (Currently Amended) The composition of claim 15 19 wherein the additive is dissolved within the cosolvent.
- 17. (Canceled)
- 18. (Currently Amended) The composition of claim 47 19 wherein the residues are at least one selected from photoresist, UV-hardened resist, X-ray hardened resist, ashed resists, carbon-fluorine containing polymer, plasma etch residues, organic process contaminants, and inorganic process contaminants.

19. (New) A composition for removing residues from the microstructure of an object comprising:

carbon dioxide wherein the carbon dioxide is in a pressurized or a supercritical fluid state;

an additive comprising a fluoride having a formula $NR_1R_2R_3R_4F$, where R_1 , R_2 , R_3 , and R_4 are each independently a hydrogen or an alkyl group, and mixtures thereof and optionally a basic compound; and

a cosolvent selected from an alcohol, dimethylacetamide, propylene glycol, dimethylsulfoxide, deionized water, acetic acid, acetone, ethanol, propanol, dimethylformamide, N-methyl-2-pyrrodine, diethylene glycol methyl ether, and mixtures thereof.

20. (New) A composition for removing residues from the microstructure of an object comprising:

from 0.001 to 8 weight percent of an additive comprising a fluoride having a formula $NR_1R_2R_3R_4F$, where R_1 , R_2 , R_3 , and R_4 are each independently a hydrogen or an alkyl group, and mixtures thereof and optionally a basic compound;

from 1 to 50 weight percent of a cosolvent selected from an alcohol, dimethylacetamide, propylene glycol, dimethylsulfoxide, deionized water, acetic acid, acetone, ethanol, propanol, dimethylformamide, N-methyl-2-pyrrodine, diethylene glycol methyl ether, and mixtures thereof; and

carbon dioxide.

- 21. (New) The composition of claim 20 wherein the additive further comprises methane.
- 22. (New) The composition of claim 20 wherein the additive further comprises a surfactant having a CFx group.